Radiation damage in *p*-type boron doped Si



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• Motivation and Method

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- Summary and conclusions

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- * The formation of deep levels limits their lifetime (V₂O)
- \star Would these problems be encountered in p-type Si?

• Method:

- Boron interstitial defects and boron-impurity complexes investigated
- Use DFT (AIMPRO) to study stability and electrical properties
- ★ Comparison with observed centres

p-type Vs. n-type





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- Fewer levels in *p*-type Si (right)



- Many levels in *n*-type (left)
 Deep level of V₂O acts a recombination centre
- Fewer levels in *p*-type Si (right)
 Mainly shallow (no deep V₂O level)











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- $B_i B_s$ is electrically inactive

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 ★ E_A = 1.2 eV (using experimental W_{B_i})

J. R. Troxell and G. D. Watkins, Phys. Rev. B 22, 921 (1980).

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 ★ Would dissociate at ~ 400°C

Boron-hydrogen complex

N. Yarykin, O. V. Feklisova and J. Weber, private communication (2003)

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Summary and conclusions Even at R.T. B_i is mobile and will form complexes

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- ★ But if H present \Rightarrow B_iB_sH_i

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$$\star \sigma_n = 10^{-13}$$
, $\sigma_p pprox 10^{-20}~{
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